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Information about obtaining **reprints** of this article or about obtaining **permission to reproduce this article** in whole or in part can be found at: http://www.sciencemag.org/about/permissions.dtl the growing crystal (4, 15), physical entrapment can occur for a wide range of organic material. This work suggests an approach for modifying the internal structures of crystals and synthesizing single-crystal composites with large, potentially accessible, internal surface areas. Potential uses for the gel method include the preparation of materials that require both high crystallinity and high surface areas, such as photovoltaic materials (31).

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2 July 2009; accepted 14 October 2009 10.1126/science.1178583

Formation of Compositionally Abrupt Axial Heterojunctions in Silicon-Germanium Nanowires

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We have formed compositionally abrupt interfaces in silicon-germanium (Si-Ge) and Si-SiGe heterostructure nanowires by using solid aluminum-gold alloy catalyst particles rather than the conventional liquid semiconductor—metal eutectic droplets. We demonstrated single interfaces that are defect-free and close to atomically abrupt, as well as quantum dots (i.e., Ge layers tens of atomic planes thick) embedded within Si wires. Real-time imaging of growth kinetics reveals that a low solubility of Si and Ge in the solid particle accounts for the interfacial abruptness. Solid catalysts that can form functional group IV nanowire-based structures may yield an extended range of electronic applications.

The most exciting applications of semiconductor nanowires—for electronic devices as well as for fundamental research into transport phenomena—do not come from compositionally uniform structures, but from heterostructure nanowires in which the composition changes along the length of the wire. These axial heterostructures are particularly important for applications such as tunnel field-effect transistors and thermoelectric devices (1-4). A prerequisite for optimal device performance in these applications is the formation of compositionally abrupt and structurally perfect junctions (5, 6). The relative ease of forming abrupt, defect-free junctions in group III-V nanowires composed of materials pairs such as InAs-InP has been key to realizing devices such as double-barrier resonant tunneling devices and single-electron transistors (3, 7–9). Yet abrupt interfaces have not been formed in group IV nanowires, creating a severe constraint on the use of group IV materials in nanowire applications. This is thought to be due to the fundamental nature of the process by which the nanowires grow.

Si and Ge nanowires are commonly fabricated using the vapor-liquid-solid (VLS) mechanism (10). In this method, droplets of a liquid catalyst are formed on a substrate via eutectic reaction between the semiconductor and a metal, typically gold, above the eutectic temperature $T_{\rm eu}$. A vapor-phase semiconductor reactant, such as silane or germane, is then introduced and is preferentially dissociated by the liquid catalyst and dissolved into the liquid. Once the concentration of semiconductor atoms in the catalyst reaches supersaturation, the semiconductor precipitates at the liquid-substrate interface. Nanowires then grow as material is added in a layer-by-layer fashion at the liquid-solid interface. To create a junction between two different semiconductors, the vapor-phase reactants are modulated during growth. This, of course, requires a catalyst suitable for the growth of both components under compatible conditions.

Group IV heterostructure nanowires containing dislocation-free Si and SiGe segments have been grown successfully using this approach (11, 12). However, the interfaces are diffuse, showing a broad composition gradient. A similar broadening of Si-Ge interfaces has also been seen for "MBE-grown" nanowires, where the same Au starting material is used but the Si and Ge are supplied by molecular beam epitaxy (13, 14). Theoretical modeling and experimental investigation (12, 15) suggest that this interface diffuseness is due to a "reservoir effect." The catalytic droplet contains a large amount of the growth species; AuSi and AuGe contain more than 20 atomic percent of Si or Ge, respectively. This means that when the reactant supply is switched, say from silane to germane, the droplet must be depleted of Si before pure Ge can be deposited. It is found (12) that the length of the compositionally graded region scales with wire diameter, as expected from the modeling (12, 15). Because interface diffuseness is due to the high solubility of Si and Ge in the catalyst, it cannot be avoided with the usual liquid semiconductor-metal catalysts. However, in solid metal catalysts the solubility of Si or Ge can be very low, so that rapid depletion of each material would be expected. Our approach to an abrupt interface in a nanowire junction structure exploits the potential of solid catalysts and uses the vapor-solid-solid (VSS) growth mechanism.

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Several solid catalysts have been used to grow Si and Ge nanowires (16-22). We ruled out the use of metal silicides or germanides (18-22) for our purpose, because of possible reservoir effects due to transformations between silicide and germanide during formation of the heterostructure. Solid Au catalyzes Ge wire growth (16), but because the reaction must be carried out below $T_{\rm eu}$ (~360°C for both Si and Ge), VSS growth is impractically slow for conventional Si and Ge reactants. Aluminum, which is of interest for photovoltaic nanowire applications because of its electronic properties in Si (23), has a higher T_{eu} (577°C) but slow Si wire growth kinetics (17, 24). To realize efficient heterojunction nanowire growth, we sought a solid catalyst that is suitable for both Si and Ge and that can provide practical growth rates. To this end, we added Al to Au catalysts (i) to raise the eutectic temperature with Si or Ge, and hence the nanowire growth temperature and growth rate under VSS, while (ii) maintaining the high reactivity known for Au. The ternary phase diagrams of Al-Au-Si and Al-Au-Ge have not been determined experimentally, but theoretical calculations predict a eutectic temperature of Si with one of the intermetallic compounds, AlAu₂, of 487°C (25). Because of the similarity in physical properties between Si and Ge, we might expect Ge to have a similar T_{eu} with AlAu₂.

Growth experiments were conducted in a transmission electron microscope (TEM) (26), because real-time observations proved useful in providing structural information during growth

Fig. 1. (A to C) Frames extracted from a movie recorded during growth of a Si nanowire (diameter 28 nm) in $3 \times$ 10⁻⁵ torr disilane as the temperature was reduced from 570°C to 503°C: (A) immediately before solidification of the catalyst (507°C); (B) just after solidification (503°C), which is evident from the faceted shape of the catalyst; (C) 14 s after (B), growth rate 5 nm/min. The growth rate is 22 nm/min in the VLS mode at 570°C. (D to I) Formation of a Si-Ge-Si heterojunction in a Si nanowire (diameter 14 nm). The Si nanowire in (D) was first grown at 510°C with 1×10^{-5} torr Si₂H₆ for 2 hours and then cooled to 360°C. The faceted surface after cooling indicates the solid state of the catalyst. (E) After flowing as well as in tuning the growth parameters (27). The catalyst was prepared by thermally evaporating Au and Al sequentially with an atomic ratio of 2:1. Two growth modes are possible in this system, the faster VLS and the slower VSS, with $T_{\rm eu}$ around the expected value (Fig. 1, A to C). Figure 1, D to I, shows the growth sequence of a Si-Ge-Si heterostructure as it forms in a single nanowire. We first grew long Si nanowires in the VLS mode and then cooled them below T_{eu} to obtain the VSS mode (Fig. 1D). Subsequent modulation in the gas source produced the junction segments effectively (Fig. 1, E to I). Under these imaging conditions, Ge exhibits darker contrast, and the sharp change between the narrow Ge layer (or "quantum dot") and the surrounding Si hints at compositionally abrupt interfaces. The VSS growth rates for Ge and Si are slower than the rapid VLS Si nanowire growth but are still practical for the purpose of growing the heterostructure.

We quantify the structural perfection and the compositional abruptness of the Si-Ge interface in Fig. 2, where we have simplified the structure by growing only a Ge layer on the tip of a Si nanowire in order to avoid ambiguity in analysis due to overlay of materials on wire sidewalls. The analysis in Fig. 2 was obtained after (rather than during) growth, allowing the use of microscopes with analytical capabilities and higher spatial resolution but requiring the sample to be exposed to air (26). In Fig. 2A we see that the interface exhibits a single crystalline structure



 5×10^{-6} torr Ge₂H₆ at 360°C for 1 min, Ge growth has begun and the catalyst has become less sharply faceted. (F) After 7 min, formation of a thin Ge layer that appears as a dark band at the Si-catalyst interface. (G) After 8.5 min of Si growth at 360°C and 1×10^{-5} torr Si₂H₆. (H) After 14 min of Si growth, the catalyst has resumed the strong facets on its surface seen in (D). (I) For demonstration purposes, the catalyst was exposed to 5×10^{-6} torr Ge₂H₆ at 360°C for 1 min again, resuming the shape seen in (F). The growth rates of the Ge and Si segments measured in (H) are 0.4 and 0.2 nm/min, respectively. The growth direction of the wires is Si[111]. The dark contrast on the Si segment in (G) to (I) is due to conformal deposition of Ge on the Si sidewalls. without obvious crystal defects such as dislocations. High-angle annular dark-field scanning TEM (HAADF-STEM; Fig. 2B) confirms the



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Fig. 2. (A) High-resolution TEM image of a Si-Ge heterojunction nanowire. A Si wire (length 500 nm, diameter 18 nm) was grown rapidly using VLS at 510°C with 1×10^{-5} torr Si₂H₆ for 2 hours, then cooled and grown for several minutes in the VSS mode at 360°C, followed by growth of a Ge segment at 360°C with 5×10^{-6} torr Ge₂H₆ for 16 min. (**B**) HAADF-STEM image of a wire (diameter 17 nm) grown under the same conditions. The inset shows the intensity profile across the interface, averaged over a 5-nm strip along the midpoint of the wire. The width of the interface is 1.3 nm. (C) HAADF-STEM image of a Si/Si_{1-x}Ge_x nanowire (diameter 21 nm). Si was grown at 510°C and 1×10^{-5} torr Si_2H_6 for 2 hours; $Si_{1-x}Ge_x$ was grown at 430°C with 2×10^{-6} torr Si₂H₆ and 1×10^{-7} torr 20% Ge₂H₆; then Si was grown at 510°C and 2 \times 10⁻⁶ torr Si_2H_6 . (**D**) EDS line profile of Si and Ge through the Si/Si_{1-x}Ge_x junction, as indicated in (C), showing a sharp transition (less than 2 nm) from Si to SiGe. The composition of the $Si_{1-x}Ge_x$ alloy segment is estimated to be Si_{0.7}Ge_{0.3}.

presence of a compositionally uniform Ge segment on the Si nanowire. The average intensity profile (Fig. 2B, inset) shows a rather narrow transition (~1.3 nm) at the interface. STEM energy dispersive x-ray spectroscopy (EDS) line profiles (26) (Fig. 2D and fig. S1) show that the composition transition occurs in less than 2 nm, in agreement with the HAADF analysis. EDS maps (Fig. 3) confirm the uniform Ge distribution in the Ge layer; they show that there is no Si or Ge in the bulk of the catalyst and no Si in the Ge (at the detection limit, $\sim 2\%$). These results can be compared with the diffuseness of interfaces measured (using similar techniques) during a comprehensive study of Si-SiGe heterostructures grown using liquid catalysts (12); wires of the diameter shown in Fig. 2 were found to have diffuse interfaces with compositional widths on the order of 18 to 24 nm.

Apart from the reservoir effect, other factors may affect the measured interface abruptness, including Si-Ge interdiffusion at the growth



Fig. 3. Composition analysis of a Si-Ge heterojunction nanowire grown under the conditions of Fig. 2A. (A to E) Bright-field TEM image (A) and false-color STEM EDS elemental maps (B to E) of Al, Si, Ge, and Au in the region [defined in (A)] of the junction in a nanowire 22 nm in diameter. The catalyst is surrounded by an amorphous shell, 2 nm thick, that forms after air exposure. The stronger Al signal in this region and the difference in interface diffuseness between the Al and Au maps suggests that the shell is aluminum oxide, consistent with the results of oxidation of AlAu alloys described in (30). (F) Line profile of the EDS intensities extracted from the elemental maps of Si, Ge, and Au. The intensity is averaged over a 3-nm strip along the midpoint of the wire.

temperature and broadening of the STEM probe. A previous study of Ge self-diffusion in $Si_{1-x}Ge_x$ $(0 \le x \le 0.5)$ under various strain conditions suggested that Si-Ge interdiffusion at the nanowire growth temperature should be slow enough to be negligible over our growth times (28). Electron beam broadening, however, does cause a noticeable error in determining interface abruptness (29). Using Goldstein's single-scattering equation (29), we estimate a beam broadening of 0.3 nm in Si and 0.6 nm in Ge (using a wire thickness of 20 nm and an electron energy of 300 keV). Adding these effects to the original 0.5-nm probe, an atomically abrupt interface should appear with a width of ~1 nm. In other words, the compositional width of our Si-Ge interface is probably less than that shown in the profiles in Figs. 2 and 3 and fig. S1, and may be below 1 nm. Any physical roughness (nonplanarity of the interface) would also contribute to the measured interface abruptness. We cannot completely rule out the possibility that some Si could remain in the catalyst, but any reservoir effect must be small, as we do not see a measurable difference between the widths of the interfaces in wires 20 nm and 10 nm in diameter (26) (fig. S1). Because Ge and Si are not detectable in the catalyst, their solubility is low, fully supporting the advantage of using a solid catalyst to reduce the reservoir effect.

During VSS growth, ledge nucleation and flow at the catalyst-wire interface is evident (fig. S2) and is expected in VSS systems (20). Here, by measuring the kinetics of individual ledge motion, we found evidence to support a solubility of Si and Ge in the solid catalyst that is low relative to the solubility in liquid Au eutectic droplets. During VSS growth of Si, we found that ledges nucleate only a short time after a previous ledge has finished propagating (fig. S2). In contrast, for VLS growth at the same overall growth rates, we observed quite different ledge flow kinetics (fig. S3): long "incubation times" (several seconds) between ledges, followed by very rapid ledge propagation at a rate too fast to measure. In VLS, it is not surprising that substantial excess Si or Ge is needed to raise the chemical potential high enough to nucleate a ledge. This excess provides a large driving force and supply for the subsequent rapid motion. For VSS, the short incubation time suggests that even a tiny amount of excess Si raises the chemical potential enough to nucleate a ledge, consistent with low solubility. In that case, the excess Si would be too small to drive the ledge very far, and subsequent motion would then be supply-limited, depending directly on the incoming flux.

The fact that ledge motion depends directly on the incoming flux is particularly relevant to the growth of SiGe alloy segments in nanowires. When growing alloy segments from liquid eutectic droplets, the composition profiles at Si-SiGe interfaces are found to be curved (1/2); in other words, the central region of the wire switches composition at a different rate relative to regions nearer the wire surface. This effect is thought to arise because, although the growth interface remains planar, the incorporation ratio of Si and Ge changes as a result of varying strain (12). Here, we expect such effects to be avoided or minimized because of the direct dependence of the deposited composition on the gas supply. Indeed, SiGe segments grown from solid catalysts (Fig. 2, C and D) by flowing disilane and digermane simultaneously show abrupt and planar Si-SiGe interfaces (<2 nm wide) and a uniform composition within the SiGe segment.

The following are some practical considerations for extending the technique of using a solid catalyst with low group IV solubility to create abrupt heterointerfaces in nanowires.

1) We have mentioned the need for a relatively high eutectic temperature, so that the VSS growth mode can be obtained at temperatures high enough to achieve reasonably fast growth rates. However, it is also useful to be able to access the VLS growth mode when needed, by means of a small increase in temperature. This was shown in Fig. 1 where the VLS mode was used to expedite Si nanowire growth, forming wire segments hundreds of nanometers in length, after which the sample was cooled to obtain VSS Si growth before forming Si-Ge interfaces or quantum dots.

2) To form wires consistently with a particular morphology (i.e., a well-defined cross-sectional shape and growth direction and no kinking), we suggest that it is advantageous to have a strong orientation relationship between the solid catalyst crystal and the wire. For the majority of wires, the AlAu₂ catalyst we have used here exhibits a large top facet and a flat shape, and this orientation forms wires that are generally unkinked.

3) The solid catalyst must be able to grow both Si and Ge segments without changes in its shape, because shape changes could alter the wire diameter.

It is our belief that other solid materials that catalyze Si and Ge wire growth should be useful in forming abrupt heterointerfaces, provided that they satisfy the requirements above in terms of eutectic temperature, the existence of a preferred orientation relationship, and minimal changes in shape between growing Si and growing Ge.

Our results show that axial Si-Ge nanowire heterostructures in which the composition is modulated at the nanometer scale can be realized by using an AlAu alloy catalyst operating via the VSS growth mechanism. This method provides control over compositional modulation that is superior to that possible with the use of conventional AuSi-AuGe liquid catalysts. The key to achieving this control is twofold: The solid state of the catalyst leads to a low solubility of Si or Ge and avoids the reservoir effect that accounts for the smearing of compositional changes, and the tuning of the eutectic temperature allows rapid growth with a VLS mode to form long uniform segments, as well as VSS growth at a slower yet practical rate for nanoscale control of interfaces,

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quantum dots, and barriers. We believe that this approach should apply to solid catalyst materials other than AlAu alloys, and indeed to wire materials other than Si and Ge, provided that the catalyst and wire material satisfy requirements for eutectic temperature, orientation, and stability. We speculate that a solid catalyst could be similarly advantageous in forming abrupt doping profiles, such as are required for highsubthreshold slope devices such as tunnel and avalanche field-effect transistors. More generally, Si and Ge device fabrication that requires sophisticated control of composition and structure can be addressed using this approach.

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- 31. We acknowledge A. Ellis and L. Gignac of IBM for their assistance with experimental aspects of this work. Supported by NSF grants DMR-0606395 and DMR-0907483 and by the University of California Energy Institute.

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26 August 2009; accepted 29 September 2009 10.1126/science.1178606

Selective Phenol Hydrogenation to Cyclohexanone Over a Dual Supported Pd–Lewis Acid Catalyst

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Cyclohexanone is an industrially important intermediate in the synthesis of materials such as nylon, but preparing it efficiently through direct hydrogenation of phenol is hindered by over-reduction to cyclohexanol. Here we report that a previously unappreciated combination of two common commercial catalysts—nanoparticulate palladium (supported on carbon, alumina, or NaY zeolite) and a Lewis acid such as AlCl₃—synergistically promotes this reaction. Conversion exceeding 99.9% was achieved with >99.9% selectivity within 7 hours at 1.0-megapascal hydrogen pressure and 50°C. The reaction was accelerated at higher temperature or in a compressed CO_2 solvent medium. Preliminary kinetic and spectroscopic studies suggest that the Lewis acid sequentially enhances the hydrogenation of phenol to cyclohexanone and then inhibits further hydrogenation of the ketone.

vclohexanone is a key raw material in the synthesis of many useful chemical intermediates, such as caprolactam for nylon 6 and adipic acid for nylon 66 (1, 2). The industrial production of cyclohexanone typically involves either the oxidation of cyclohexane (3, 4) or the hydrogenation of phenol. The former route requires high temperature and generates byproducts such as cyclohexanol and organic acids that complicate purification, and the yield of cyclohexanone is usually low. The phenol hydrogenation route is undertaken through either two-step or one-step processes. In the two-step procedure, phenol is first hydrogenated to cyclohexanol, which in turn is dehydrogenated to cyclohexanone at high temperature. The one-step selective hydrogenation of phenol to cyclohexanone is advantageous from an efficiency standpoint, and

the reaction can be conducted in either the gas phase or liquid phase. The gas-phase phenol hydrogenation is usually performed in the temperature range of 150° to 300°C over supported Pd catalysts (5-9), and different supports have been used, including alumina, that may act as Lewis acids (9). The gas-phase process can be carried out easily in continuous reactors for higher throughput. Liquid-phase phenol hydrogenation offers cost and energy savings, because the reaction can be performed at relatively low temperatures (10-15). Many researchers have contributed to this area, and multiple catalysts have been screened, such as Rh/C (10), Rh/C nanofiber (11), Pd/hydrophilic C (12), Ru/poly(N-vinyl-2pyrrolidone) (PVP) (13), Pd/Mg and Pd/Fe (14), mesoporous Ce-doped Pd (15), and Pd/C (16). However, the attainment of high selectivity (>95%) at elevated conversion (>80%) with a satisfactory rate is a great challenge (8, 17), because the cyclohexanone product can be further hydrogenated to cyclohexanol under the reaction conditions (7, 15).

We report here that Pd/C, Pd/Al₂O₃, and Pd/NaY zeolite (*18*) (NaY zeolite is hereafter denoted NaY) catalysts and solid Lewis acids show excellent synergy in the hydrogenation of phenol to cyclohexanone, together substantially enhancing both activity and selectivity. The reaction can be carried out effectively at temperatures as low as 30°C, and >99.9% conversion of phenol is observed with >99.9% selectivity to cyclohexanone. Separation of the product from the catalyst–Lewis acid system is simple, and the catalyst system can be reused directly. This route has great potential for industrial application.

Our experiments (18) showed that dichloromethane is the best reaction solvent among several tested (table S2). Table 1 presents the results of phenol hydrogenation under different conditions over Pd/C, Pd/Al2O3, and Pd/NaY catalysts with and without AlCl₃. The conversion of phenol was very low, and considerable byproduct was produced when only the Pd/C catalyst was used (Table 1, entry 1), and the reaction did not occur at all when only Lewis acid (AlCl₃) was used (Table 1, entry 2). When Pd/C and AlCl₃ were used at the same time, the reaction proceeded with a selectivity of >99.9% up to complete conversion at 1.0 MPa of H₂ and a temperature at or below 50°C (Table 1, entries 3 to 5). At higher temperature, the reaction reached completion in 1 hour and the selectivity remained >99% (Table 1, entries 9 and 10). With other conditions fixed, an increase in hydrogen pressure (Table 1, entries 6 to 12) shortened the time to completion but slightly reduced the selectivity to cyclohexanone. Other Lewis acids were also effective in promoting the reaction [Table 1, entries 13 to 18; see also fig. S7 and supporting online material (SOM) text]. The activity and selectivity of the reaction using Pd/Al₂O₃ and Pd/NaY (18) were also enhanced effectively by AlCl₃ (Table 1, entries 19 to 26). The prospects for recycling Pd/C-ZnCl₂ were tested (18), and

the results indicated that the catalyst system could

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